## HIGH POWER LASER BEAM PROFILER SYSTEM SOLUTION / NFP MEASUREMENT SYSTEM

# SIMPLIFIED OPTICAL BEAM NFP MEASUREMENT SYSTEM FOR HIGH POWER LASER

Simplified optical beam profile and NFP measurement system especially targeting for high power laser

Simplified optical beam NFP measurement system for high power laser is a optical beam profile measurement system targeting for ~10W class high power laser. NFP measurement optics for high power laser **M-Scope type HL** is used. The light flux emitted from high power laser sample is attenuated by beam sampler unit placed before objective lens, and is further attenuated by ND filter at subsequent stage. The NFP image that has been attenuated to appropriate beam power is captured and image processing analysis is performed.

## [Features]

- OM-Scope type HL, simplified NFP measurement optics for high power laser
- Attenuation of incident beam with beam sampler placed before objective lens and ND filters
  Optical magnification is maximum 20x (option, 10x objective lens and 2x intermediate lens)
- Optical beam analysis module AP013, specially designed high-functional image processing software for optical beam profile analysis
   All-in-one package of PC, optical beam analysis software, detector driver, calibration data.
  - High-performance image processing software for optical beam profile measurement **Optimetrics BA Standard** is pre-installed.

# [Standard component]

#### Optics

# • M-Scope type HL

\*Please specify the measurement wavelength from 400~1100 range because AR coating to some optical parts is required. Objective lens

- M-Plan Apo 10× (fixed)
- ODetector selection
- 400-1100nm : Hi-resolution CMOS detector ISA071/ISA071GL Optical beam analysis module AP013
- PC for image processing, optical beam analysis software Optometrics BA Standard, detector driver, calibration data, USB key

OAccessories

https://www.synos.jp

• Cables, instruction manuals, etc.

#### [Option]

- Option for optics (for **M-Scope type HL**)
  - 2× intermediate lens port MS-OP011-RL2
  - Intermediate lens unit that doubles the overall magnification  $\bullet$  1/2× intermediate lens port **MS-OP011-RLH**
  - Intermediate lens unit that halves the overall magnification • Coaxial epi-illumination port MS-OP011-CEP
- Coaxial epi-illumination port with removable half mirror  $\bigcirc$  ND filter (for M-Scope type HS, dedicated 30 $\phi$ )
  - Visible (400~700nm): **NDF-5** (5 types per set)
- NIR (700~1100nm): **NDF NIR-5** (5 types per set) Coaxial epi-illumination light source
- Visible~NIR: LED epi-illumination system

### Optics bench

• Optics bench for fiber measurement with manual stages

\*Pixel resolution: The measurement length equivalent to 1 pixel of the detector calculated from filed of view and sensor pitch of the detector. \*The optical magnification when using **MS-OP011-RL2** is 2 times the magnification in the table on the left, and the actual field of view and pixel resolution are 1/2. The maximum optical magnification is 20x when using

\* The optical magnification when using the **MS-OP011-RLH** is 1/2 of each magnification in the table on the left, and the actual field of view and pixel

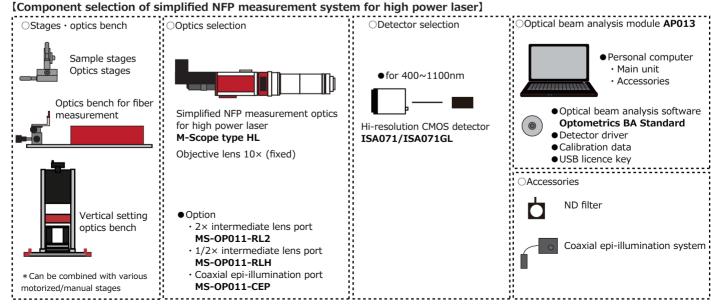
• Vertical setting optics bench

a 10x objective lens

resolution are 2 times.

### [Detector selection, field of view, pixel resolution (approx. value)]

Detector	High resolution CMOS detector	
	ISA071/ISA071GL	
Spectral range	400~1100nm	
Sensor size	1/1.8 inch	
Total pixels	2048×1536	
Pixels pitch	3.45µm	
Magnification	Field of view	Pixel resolution
	(unit:mm)	(unit:µm)
10×	0.7×0.52	0.345



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